

BM 300

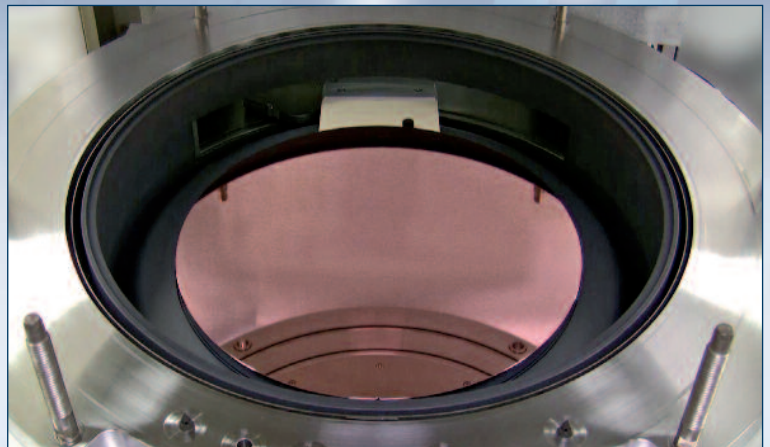
AIXTRON



300 mm Wafer-scale Production of Carbon Nanotubes and Graphene

Features

- 1050° C substrate heater
- Uniform gas delivery through showerhead
- Precise precursor concentration control
- Heater to showerhead gap adjust
- Wafer rotation during process
- ARGUS real-time wafer temperature mapping
- Optical ports at normal incidence to wafer



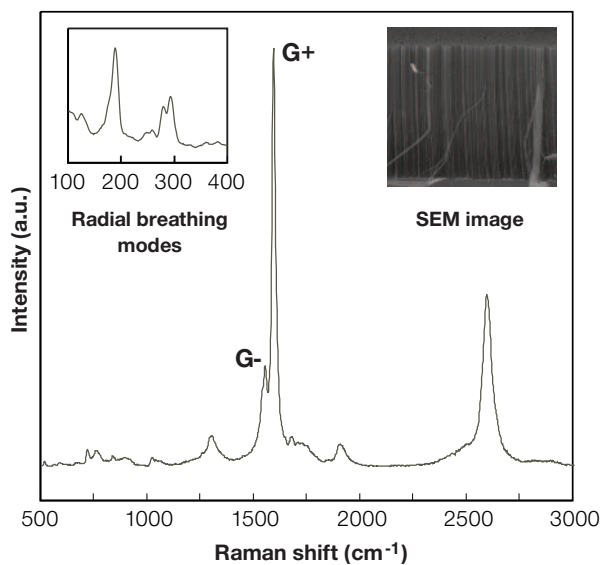
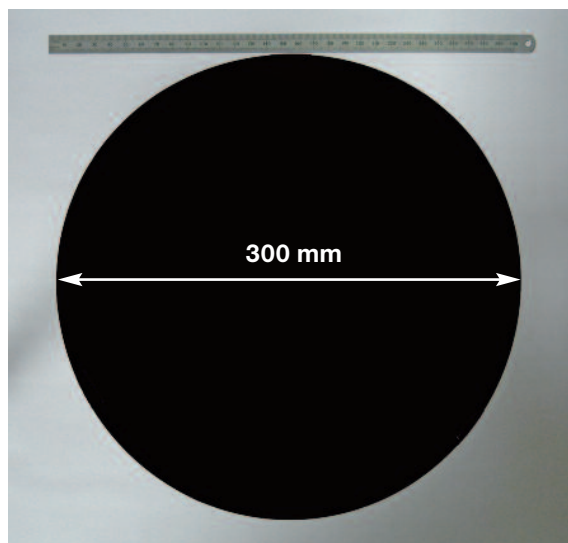
Advanced Heater Design for Outstanding Uniformity



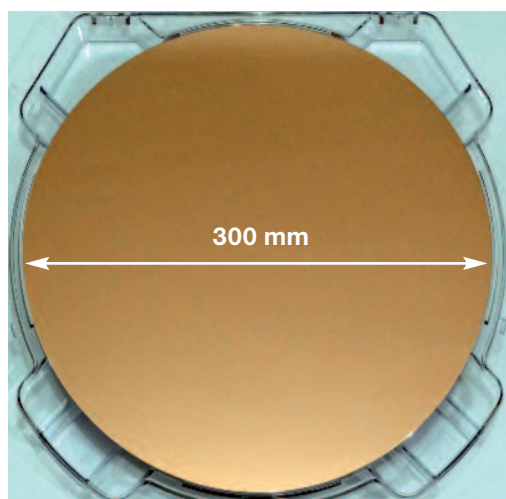
BM 300 Process Module and Handler System



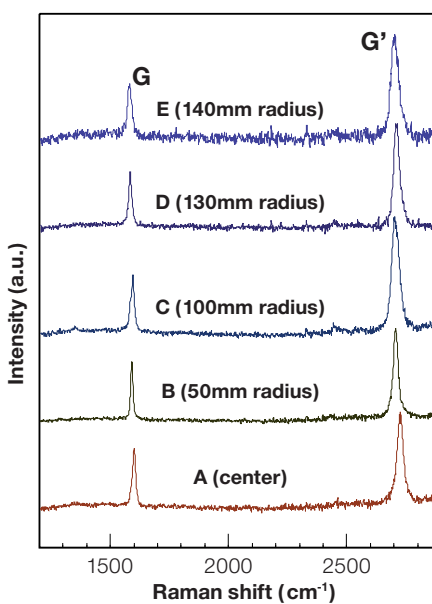
Results



High Quality Carbon Nanotubes



Courtesy of AIST Green Nanoelectronics Center (GNC)



High Quality Graphene